

**Notice of References Cited**

Applicant/Patent

FIGURA et al.

Application/Control No.

09/471,460

Examiner

Calvin Lee

Art Unit

2825

Page 1 of 1

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<sup>1</sup> A copy of this reference is not being furnished with this Office action. See MPEP § 707.05(a).<sup>1</sup> Dates in MM-YYYY format are publication dates.<sup>2</sup> Classifications may be U.S. or foreign.